

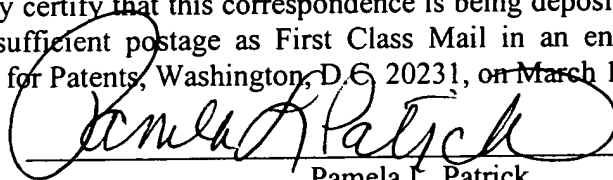
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Docket No. 09/197,534



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Pamela L. Patrick

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT application of)
Shunpei YAMAZAKI et al.)
Serial No. 09/197,534) Group Art Unit: 2823
Filed: November 23, 1998) Examiner: W. Coleman
For: LASER PROCESS) Date: March 11, 2002

AMENDMENT

Commissioner for Patents
Washington, D.C. 20231

Sir:

In response to the Office Action of October 9, 2001, please amend the above-identified application as follows.

IN THE CLAIMS:

Claims 1, 2, 4-6, 8-10, 12-14, 16, 17 and 19 are presented below in their amended form. The amendments to the above noted claims are outlined in an Attachment to the Amendment using the conventional indication method of bracketing and underlining.

1. (Amended) A method of manufacturing a semiconductor device comprising the steps of:

preparing a plurality of semiconductor islands over a glass substrate;
subjecting said semiconductor islands to an ion doping;

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